## Amendments to the Claims:

This listing of claims will replace all prior versions, and listings of claims in the application:

## **Listing of Claims:**

- 1. (Previously Presented) A sensor comprising:

  a substrate bearing a first electrode coplanar with a second electrode; and
  a dielectric seismic mass overlying and separated from the electrodes by a gap,
  wherein movement of the seismic mass parallel to the electrode plane alters a rate of occupation
  of space by the dielectric material in a fringe electric field arising between the electrodes.
- 2. (Original) The sensor of claim 1 wherein the first and second electrodes are comb-shaped.
- 3. (Original) The sensor of claim 1 wherein the dielectric seismic mass comprises Parylene.
- 4. (Original) The sensor of claim 1 wherein the seismic mass is perforated by holes.
  - 5. (Canceled)
- 6. (Withdrawn) The sensor of claim 13 wherein movement of the seismic mass normal to the electrode plane alters the rate of occupation of space by the dielectric material.
  - 7. (Canceled)
- 8. (Previously Presented) The sensor of claim 1 further comprising a third electrode separated from a fourth electrode on the substrate, wherein seismic mass defines a first hole between the first and second electrodes, and a second hole between the third and fourth electrodes, the second hole offset in pitch from the first hole.

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- 9. (Original) The sensor of claim 1 further comprising a beam in contact with an anchor portion and configured to support the dielectric mass over the electrodes.
  - 10. (Original) The sensor of claim 9 wherein the beam exhibits a linear shape.
  - 11. (Canceled)
- 12. (Original) The sensor of claim 9 wherein the beam is configured to accommodate movement of the seismic mass parallel to the electrode plane.
- 13. (Withdrawn) A sensor comprising:
  a substrate bearing a first electrode coplanar with a second electrode;
  a dielectric seismic mass overlying and separated from the electrodes by a gap;
  and

a beam in contact with an anchor portion and configured to support the dielectric mass over the electrodes, wherein the beam exhibits a spiral shape.

14. (Original) The sensor of claim 1 wherein the dielectric seismic mass and the beam comprise integral features of a dielectric layer.

15-24. (Canceled)